Advanced Surface Processes for Optoelectronics

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Advanced Surface Processes for Optoelectronics

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Preface

The field of opto-electronics is advancing at a rapid pace with the discovery of novel material systems as well as new processing ideas. The last decade has seen the maturing of technologies such as ion implantation of opto-electronic materials, energetic-beam processing of surfaces, epitaxy and heteroepitaxy of lattice matched and non-lattice matched systems, and novel growth techniques such as chemical beam epitaxy and energetic-beam assisted growth. The field has further benefited from understanding metal surface reactions to form controlled barriers, and the development of techniques to fabricate sub-micron structures both above and below the surfaces of solids. The aim of this symposium was to bring together the diverse group of researchers involved in these multifaceted fields. We have accomplished a successful beginning at the 1988 MRS Spring Meeting in Reno. We would particularly like to thank all the contributors and referees and would like to acknowledge the following session chairmen: E. Weber, J. Merz, E.H. Lee, S.J. Pearton, C.J. Palmstrøm, E. Yablonovich, and A. Scherer for their stimulating participation.

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